ABSTRACT

Contamination measurement station and method for a semiconductor substrates transport pod

The invention concerns a measurement station for the measurement of particle contamination of a transport pod for the conveyance and atmospheric storage of semiconductor substrates, such pod comprising a casing capable of being closed by means of a removable access door, such station comprising:

- an interface (5) capable of coupling to a casing of a transport pod (3) instead of the said door, the interface (5) comprising at least one injection nozzle (9) arranged at one mobile end of a pipe protruding from the said interface to direct a jet of gas in a perpendicular direction towards a portion of the wall (13) on the inside (10) of the said casing coupled to the said measurement station, so as to detach particles (11) from the said casing (3) by the impact of the gas jet on the said wall (13), and
- a measurement device (7) comprising a vacuum pump (17), a particle counter (19), and a measurement conduit (21) of which an inlet (23) leads to the inside (10) of the said casing (3), and of which an outlet (25) is coupled to the vacuum pump (17), the measurement conduit (21) being furthermore connected to the particle counter (19), to connect the inside (10) of the casing of the transport pod (3) coupled to the said measurement station with the particle counter (19).

The invention also concerns a method for the measurement of particle contamination of a transport pod for the conveyance and atmospheric storage of semiconductor substrates.

FIGURE: 1